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SEC.584

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of

Ki-sang Kim et al.

Group Art Unit: 1763

Serial No.: 09/237,229

Examiner: S. MacArthur

Filed: January 26, 1999

#16 EAE  
8/17/01  
MW

For: MULTI-CHAMBER SYSTEM HAVING COMPACT INSTALLATION SET-UP FOR  
AN ETCHING FACILITY FOR SEMICONDUCTOR DEVICE MANUFACTURING

**AMENDMENT UNDER 37 C.F.R. §1.116**

Honorable Assistant Commissioner for Patents  
Washington, D.C. 20231

Date: August 15, 2001

Sir:

In response to the Final Office Action dated May 21, 2001, the following  
amendments and remarks are respectfully submitted in connection with the above-  
identified application.

**In the Claims:**

Please cancel claim 23 without prejudice or disclaimer of the subject matter  
contained therein.

The following replacement claims are respectfully submitted:

20. (Three Times Amended) A multi-chamber system of an etching facility for  
manufacturing semiconductor devices comprising:

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AUG 17 2001  
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